IN THE SPECIFICATION

Please replace the paragraph beginning at page 5, line 11, with the following rewritten paragraph:

The method includes: using the mask with the repeated pattern, for example, having a pattern width of 2 μ m and pitch of $0.3~\mu$ m formed thereon to form, for example, a polycrystal having a length of 2 μ m and width of 0.3 μ m.